



Eric Donzier
Founder & C.E.O.
Openfield Technology

13 rue de Limoges • 78000 Versailles, France
Phone: +33 (0)6 13 12 41 84 • Fax: +33 (0)9 82 43 83 09 • E-Mail: edonzier@openfield-technology.com

Executive Profile

Results driven technology leader with 20 years of experience in innovative creation, products development management, strategic planning, operations leading & financial responsibility

Education

Paris XI-Orsay University

D.E.A.(Master of Science Degree), concentration in microelectronics and integrated optics

ESIEE (Ecole Supérieure d'Ingénieurs en Electrotechnique et Electronique), Paris Marne La Vallée
Engineering Degree, concentration in ASICs design

Professional Experience

OpenField, Versailles - FRANCE

Since April 2011

Founder & CEO of OpenField, a technology startup company developing, manufacturing and commercializing instrumentation for harsh environments. A portfolio of innovative sensors based on micro-systems is under development covering pressure, temperature and fluid properties analysis with applications for the Oil & Gas industry, geothermal management and underground carbon sequestration monitoring.

MEMSchlumberger, Elancourt - FRANCE

2004 to 2011

General Manager of the Schlumberger Internal Venture on MEMS technology. Started MEMSchlumberger, an independent corporate venture under the Engineering Manufacturing Sustaining branch of Schlumberger to develop new sensor products for well drilling and oil field production. In 2010, \$6M was generated in revenue with a team of 12 persons that delivered key technology to Schlumberger Business Segments such as Wireline, Drilling and Measurements and Testing.

Schlumberger Doll Research, Ridgefield CT - USA

2001 to 2004

Research Director for "Formation Evaluation" department. Managed a \$9M research budget with 55 scientists and engineers working in the various fields of physics and technology, developing next generation electromagnetic, acoustic, optical & RMN tools.

Schlumberger Cambridge Research, Cambridge - UK

1999 to 2001

Program manager for Micro-Nano technologies, introduced several innovative sensor concepts in the field of fluid property sensing for Reservoir Monitoring and Control.

Schlumberger Riboud Product Centre , Clamart - FRANCE 1994 to 1999
Head of the Electronics Technology Department with 15 employees and a \$6M budget. Launched and managed several advanced programs on high temperature electronics, Asics, Multi-Chip-Modules, opto-electronics and micro-sensors internally or in contract with external partners.

Schlumberger Flopetrol , Melun - FRANCE 1991 to 1994
Project leader for silicon pressure sensor development and fiber optic local probes development for multi-phasic flow measurement.

Thales (Sextant Avionique) - FRANCE 1988 to 1991
Research engineer, developed an integrated magnetic field sensor based on an innovative micro-resonator principle. Invention Granted 1st price for French research.

Paris XI university, Orsay - FRANCE
Professor, in charge of a course program on micro-sensors for DEA (MS degree students) and ESIEE microelectronics engineering school.

Patents

US 5509312 « Diaphragm pressure sensor including anti-stock protection means and gradiomanometer incorporating such a sensor »
US 5736650 « Venturi flow meter for measurement in a fluid flow passage »
US 6615664 « Method of measuring pressure by means of a pressure gauge having a resonant element »
US 6966228 « Resonator-type microelectronic pressure sensor that withstands high pressures »
US 5956132 « Method and apparatus for optically discriminating between the phases of a three-phase fluid »
US 7152466 « Methods and apparatus for rapidly measuring pressure in earth formations »
US 7434457 « Fluid property sensors »
US 7673679 « Protective barriers for small devices »
US 7958772 « Density and viscosity sensor »
US 8061219 « Flow restriction insert for differential pressure measurement »
US 2009/0302221 A1 « Apparatus and method for optically determining the presence of carbon dioxide»
EP2028341 A1 « A device and method for analyzing light chemical compounds»
US 2010/051353 A1 « Method and apparatus for differential pressure measurement»
US 2010/052147 A1 « Micro-thermal conductivity detector, method to fabricate such and chromatography system using such»
IB2011/052145 « Apparatus and method for phase equilibrium with in-situ sensing »
IB2010/050740 « Micro-Valve and Micro-Fluidic Device Using Such »